Gases Japan TC Chapter and Facilities Japan TC Chapter Joint Meeting Meeting Summary and Minutes (Draft)

SEMI Japan Standards Summer 2017 Meetings
June 23, 2017, 15:00-17:00
SEMI Japan, Tokyo, Japan

TC Chapter Announcements

Gases Japan TC Chapter:
SEMI Japan Standards 2017 Winter Meetings
Tuesday, December 12, 2017, 13:00-15:00
SEMI Japan, Tokyo, Japan

Facilities Japan TC Chapter:
SEMI Japan Standards 2017 Winter Meetings
Tuesday, December 12, 2017, 13:00-15:00
SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs of Gases Japan TC Chapter:
Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

Co-Chairs of Facilities Japan TC Chapter:
Hiromichi Enami (Hitachi High Technologies), Isao Suzuki (MKS Japan)

SEMI Staff: Mizue Iwamura (SEMI Japan)

<table>
<thead>
<tr>
<th>Company</th>
<th>Last</th>
<th>First</th>
<th>Company</th>
<th>Last</th>
<th>First</th>
</tr>
</thead>
<tbody>
<tr>
<td>Hitachi High Technologies</td>
<td>Enami</td>
<td>Hiromichi</td>
<td>HORIBA STEC</td>
<td>Isobe</td>
<td>Yasuhiro</td>
</tr>
<tr>
<td>Flow Techno Service</td>
<td>Ishihara</td>
<td>Seiji</td>
<td>MKS Japan</td>
<td>Suzuki</td>
<td>Isao</td>
</tr>
<tr>
<td>Fujikin</td>
<td>Hirose</td>
<td>Takashi</td>
<td>Tokyo Electron</td>
<td>Mashiro</td>
<td>Supika</td>
</tr>
<tr>
<td>Fujikin</td>
<td>Machii</td>
<td>Yoshifumi</td>
<td>Tokyo Electron Tohoku</td>
<td>Okabe</td>
<td>Tsuneyuki</td>
</tr>
<tr>
<td>Fujikin</td>
<td>Kitano</td>
<td>Masafumi</td>
<td>Tri Chemical Laboratories</td>
<td>Hiraki</td>
<td>Tadaaki</td>
</tr>
<tr>
<td>Hitachi Metals FineTech</td>
<td>Jinbo</td>
<td>Katsuhiro</td>
<td>SEMI Japan</td>
<td>Iwamura</td>
<td>Mizue</td>
</tr>
<tr>
<td>HORIBA STEC</td>
<td>Shimizu</td>
<td>Tetsuo</td>
<td></td>
<td></td>
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</tr>
</tbody>
</table>

*alphabetical order by Company name

Table 2 Leadership Changes

Gases Japan TC Chapter

<table>
<thead>
<tr>
<th>WG/TF/SC/TC Name</th>
<th>Previous Leader</th>
<th>New Leader</th>
</tr>
</thead>
<tbody>
<tr>
<td>5-year-review TF</td>
<td>Yoshifumi Machii (Fujikin)</td>
<td>Masafumi Kitano (Fujikin)</td>
</tr>
</tbody>
</table>

Facilities Japan TC Chapter

None.
Table 3 Committee Structure Changes
Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 4 Ballot Results
Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter
Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 6 Authorized Activities
Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 7 Authorized Ballots
Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 8 SNARF(s) Granted a One-Year Extension
Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.
Table 9 SNARF(s) Abolished

Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 10 Standard(s) to receive Inactive Status

Gases Japan TC Chapter

<table>
<thead>
<tr>
<th>Standard Designation</th>
<th>Title</th>
</tr>
</thead>
<tbody>
<tr>
<td>SEMI F82-1012</td>
<td>SPECIFICATION FOR DIMENSION OF MASS FLOW CONTROLLER/MASS FLOW METER FOR 1.125 INCH TYPE SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F83-1012</td>
<td>SPECIFICATION FOR DIMENSION OF TWO PORT COMPONENTS (EXCEPT MFC/MFM) FOR 1.125 INCH TYPE TWO FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F84-1012</td>
<td>SPECIFICATION FOR DIMENSION OF THREE PORT COMPONENTS (EXCEPT MFC/MFM) FOR 1.125 INCH TYPE TWO FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F85-1012</td>
<td>SPECIFICATION FOR DIMENSION OF ONE PORT COMPONENTS FOR 1.125 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F86-1012</td>
<td>SPECIFICATION FOR DIMENSION OF TWO PORT COMPONENTS (EXCEPT MFC/MFM) FOR 1.125 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F87-1012</td>
<td>SPECIFICATION FOR DIMENSION OF THREE PORT COMPONENTS (EXCEPT MFC/MFM) FOR 1.125 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F88-1012</td>
<td>SPECIFICATION FOR DIMENSION OF STANDARD SIZE MASS FLOW CONTROLLERS AND MASS FLOW METERS FOR 1.5 INCH TYPE SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F90-1012</td>
<td>SPECIFICATION FOR DIMENSION OF STANDARD SIZE TWO PORT COMPONENTS (EXCEPT MFC/MFM) FOR 1.5 INCH TYPE TWO FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F91-1012</td>
<td>SPECIFICATION FOR DIMENSION OF COMPACT SIZE TWO PORT COMPONENTS (EXCEPT MFC/MFM) FOR 1.5 INCH TYPE TWO FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F92-1012</td>
<td>SPECIFICATION FOR DIMENSION OF COMPACT SIZE THREE PORT COMPONENTS FOR 1.5 INCH TYPE TWO FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F93-1012</td>
<td>SPECIFICATION FOR DIMENSION OF ONE PORT COMPONENTS FOR 1.5 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F94-1012</td>
<td>SPECIFICATION FOR DIMENSIONS OF TWO PORT COMPONENTS (EXCEPT MFC/MFM) FOR 1.5 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
<tr>
<td>SEMI F95-1012</td>
<td>SPECIFICATION FOR DIMENSION OF THREE PORT COMPONENTS FOR 1.5 INCH TYPE FOUR FASTENER CONFIGURATION SURFACE MOUNT GAS DISTRIBUTION SYSTEMS</td>
</tr>
</tbody>
</table>
Table 11 New Action Items
Gases Japan TC Chapter
None.

Facilities Japan TC Chapter
None.

Table 12 Previous Meeting Action Items
Gases Japan TC Chapter

<table>
<thead>
<tr>
<th>Item #</th>
<th>Assigned to</th>
<th>Details</th>
</tr>
</thead>
<tbody>
<tr>
<td>Gas161213-1</td>
<td>SEMI Staff</td>
<td>To watch the progress of Doc.5155, New Standard, Guide for Facilities Data Package for Semiconductor Equipment Installation by Building Information Modeling (BIM) for Semiconductor Capital Equipment TF of NA ... Closed</td>
</tr>
</tbody>
</table>

Facilities Japan TC Chapter
None.

[Common Part 1]

1 Welcome, Reminders, and Introductions
Hiromichi Enami, committee co-chair, called the meeting to order at 15:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01_02_Required_Elements_Reg_20150327_E+J.pdf

2 Review of Previous Meeting Minutes
The TC Chapter reviewed the minutes of the previous meeting.

Motion: To approve the minutes of the previous meeting with an editorial change.
By / 2nd: Seiji Ishihara (Flow Techno Service) / Tetsuo Shimizu (HORIBA STEC)
Discussion: None
Vote: 11 in favor and 0 opposed. Motion passed.

3 SEMI Staff Report
Mizue Iwamura gave the SEMI staff report. This report included SEMI Global 2017 Calendar of Events, Global Standards Meeting Schedule, SEMICON WEST, 2017 Critical Dates for SEMI Standards Ballots, A&R Ballot Review, SEMI Standards Publication, JRSC Organization Chart, SEMI TSUSHIN Information, Global Staff Assignment and Staff Contact Information.

Attachment: 04_00_SEMI Staff Report 20170614_r3.pdf
4 Liaison Reports

4.1 Facilities North America TC Chapter
Mizue Iwamura (SEMI Japan) reported for the Facilities North America TC Chapter as attached.
Attachment: 05_01_NA F&G Liaison Report April2017.pdf

4.2 Gases North America TC Chapter
Mizue Iwamura (SEMI Japan) reported for the Gases North America TC Chapter as attached.
Attachment: 05_01_NA F&G Liaison Report April2017.pdf

4.3 Gases Europe TC Chapter Report
None.

4.4 Facilities Korea TC Chapter Report
None.

[Gases Japan TC Chapter Part]

5 Subcommittee and Task Force Reports

5.1 Gas Panel and Metal Seal Test Methods Task Force
None.

5.2 5-year-review Task Force
See Old Business.

5.3 Live Gas Flow Rate Task Force
Tetsuo Shimizu (HORIBA STEC) reported for the Live Gas Flow Rate Task Force. The Task Force met earlier in the day. Of note:
- Round robin test has done by several companies at National Institute of Advanced Industrial Science and Technology (AIST), and Tetsuo Shimizu (HORIBA STEC) reviewed the summary of the last test results.

6 Old Business

6.1 5 Year Review Check
Yoshifumi Machii (Fujikin) addressed the committee on this topic.

Motion: To approve 13 SEMI Standards to get “inactive” status. 13 SEMI Standards are as follows; SEMI F82-1012, SEMI F83-1012, SEMI F84-1012, SEMI F85-1012, SEMI F86-1012, SEMI F87-1012, SEMI F88-1012, SEMI F90-1012, SEMI F91-1012, SEMI F92-1012, SEMI F93-1012, SEMI F94-1012, SEMI F95-1012.

By / 2nd: Yoshifumi Machii (Fujikin) / Seiji Ishihara (Flow Techno Service)

Discussion: There is few possibility to revise those SEMI standards.

Vote: 10 in favor and 0 opposed. Motion passed.
7 New Business
Yoshifumi Machii (Fujikin) addressed the committee on this topic.

Motion: To approve Yoshifumi Machii (Fujikin) to step down from 5-year-review TF, and to approve Masafumi Kitano (Fujikin) to be a leader of 5-year-review TF.

By / 2nd: Yoshifumi Machii (Fujikin) / Isao Suzuki (MKS Japan)

Discussion: None.

Vote: 10 in favor and 0 opposed. Motion passed.

[Facilities Japan TC Chapter Part]

8 Subcommittee and Task Force Reports

8.1 F1 Revision Task Force
The committee discussed to discharge F1 Revision Task Force in next committee. The committee will ask Shuji Moriya (Tokyo Electron Yamanashi) to continue F1 Revision Task Force or not, because Yoshifumi Machii (Fujikin) will step down from the leader of F1 Revision Task Force as well. Thus, there are no activities recently.

9 Old Business

9.1 5 Year Review Check
Yoshifumi Machii (Fujikin) addressed the committee on this topic.

Motion: To approve 2 SEMI Standards to get “inactive” status. 2 SEMI Standards are as follows; SEMI F1-0812, SEMI F106-1012.

By / 2nd: Yoshifumi Machii (Fujikin) / Seiji Ishihara (Flow Techno Service)

Discussion: There is few possibility to revise those SEMI standards.

Vote: 10 in favor and 0 opposed. Motion passed.

10 New Business

None.

[Common Part 2]

11 Next Meeting and Adjournment
The next meeting of the Gases Japan TC Chapter is scheduled for Tuesday, December 12, 2017, 13:00-15:00, SEMI Japan, Tokyo, Japan.

The next meeting of the Facilities Japan TC Chapter is scheduled for Tuesday, December 12, 2017, 13:00-15:00, SEMI Japan, Tokyo, Japan.

See http://www.semi.org/en/events for the current list of meeting schedules.

Having no further business, a motion was made to adjourn. Adjournment was at 17:00.
Respectfully submitted by:
Mizue Iwamura
Coordinator, Standards
SEMI Japan
Phone: +81.3.3222.5760
Email: miwamura@semi.org

Minutes approved by:

<table>
<thead>
<tr>
<th>Hiromichi Enami (Hitachi High Technologies), Co-chairs</th>
<th>October 24, 2017</th>
</tr>
</thead>
<tbody>
<tr>
<td>Isao Suzuki (MKS Japan), Co-chairs</td>
<td>October 24, 2017</td>
</tr>
</tbody>
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Table 13 Index of Available Attachments

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</tbody>
</table>

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.